


EE C245 - ME C218
Introduction to MEMS Design
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Lecture Module 10: Resonance Frequency


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Lecture Outline


- Reading: Senturia, Chpt. 10: §10.5, Chpt. 19
- Lecture Topics:
 - ↗ Estimating Resonance Frequency
 - ↗ Lumped Mass-Spring Approximation
 - ↗ ADXL-50 Resonance Frequency
 - ↗ Distributed Mass & Stiffness
 - ↗ Folded-Beam Resonator

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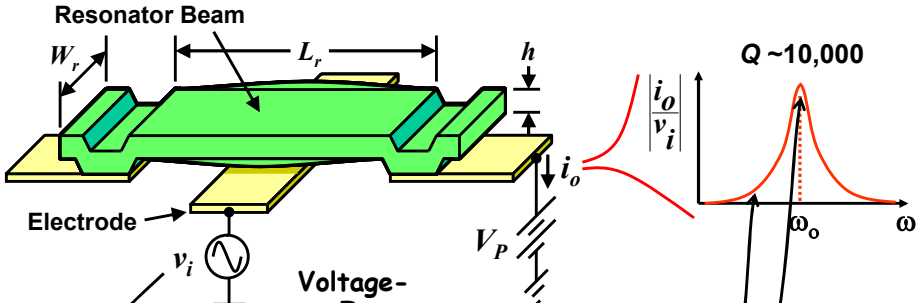


Estimating Resonance Frequency

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Clamped-Clamped Beam μ Resonator



Resonator Beam
 W_r , L_r , h

Electrode
 v_i

Voltage-to-Force Capacitive Transducer
 V_P

Sinusoidal Excitation
 $v_i = V_i \cos[\omega_o t] \rightarrow f_i = F_i \cos[\omega_o t]$

Sinusoidal Forcing Function
 i_o

$Q \sim 10,000$

ω , ω_o

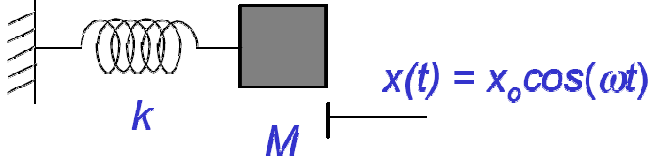
- $\omega \neq \omega_o$: small amplitude
- $\omega = \omega_o$: maximum amplitude \rightarrow beam reaches its maximum potential and kinetic energies

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Estimating Resonance Frequency

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- Assume simple harmonic motion:



$x(t) = x_o \cos(\omega t)$

- Potential Energy:

$$W(t) = \frac{1}{2} kx^2(t) = \frac{1}{2} kx_o^2 \cos^2(\omega t)$$

- Kinetic Energy:

$$K(t) = \frac{1}{2} M\dot{x}^2(t) = \frac{1}{2} Mx_o^2 \omega^2 \sin^2(\omega t)$$

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Estimating Resonance Frequency (cont)

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- Energy must be conserved:
 - Potential Energy + Kinetic Energy = Total Energy
 - Must be true at every point on the mechanical structure

Occurs at peak displacement

Occurs when the beam moves through zero displacement

$$W_{\max} = \frac{1}{2} kx_o^2 = K_{\max} = \frac{1}{2} M\omega^2 x_o^2$$

Maximum Potential Energy Stiffness Displacement Amplitude Maximum Kinetic Energy Mass Radian Frequency

- Solving, we obtain for resonance frequency:

$$\omega = \sqrt{\frac{k}{M}}$$

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Example: ADXL-50

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- The proof mass of the ADXL-50 is many times larger than the effective mass of its suspension beams
 - Can ignore the mass of the suspension beams (which greatly simplifies the analysis)
- Suspension Beam: $L = 260 \mu\text{m}$, $h = 2.3 \mu\text{m}$, $W = 2 \mu\text{m}$


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Lumped Spring-Mass Approximation

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- Mass is dominated by the proof mass
 - 60% of mass from sense fingers
 - Mass = $M = 162 \text{ ng}$ (nano-grams)
- Suspension: four tensioned beams
 - Include both bending and stretching terms [A.P. Pisano, BSAC Inertial Sensor Short Courses, 1995-1998]

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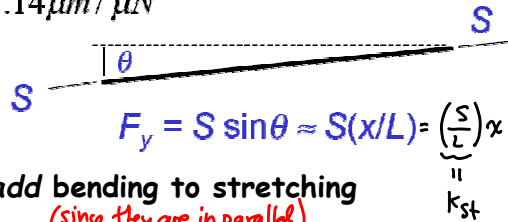


ADXL-50 Suspension Model

- Bending contribution:

$$k_b^{-1} = (1/k_c + 1/k_e) = 2 \left[\frac{(L/2)^3}{3E(Wh^3/12)} \right] = \frac{L^3}{EWh^3} = 4.2 \mu\text{m} / \mu\text{N}$$
- Stretching contribution:


$$k_{st}^{-1} = L/S = \frac{L}{\sigma_r Wh} = 1.14 \mu\text{m} / \mu\text{N}$$



$F_y = S \sin \theta \approx S(x/L) = \underbrace{\left(\frac{S}{L}\right)}_{k_{st}} x$
- Total spring constant: *add bending to stretching*
(since they are in parallel)

$$k = 4(k_b + k_{st}) = 4(0.24 + 0.88) = 4.5 \mu\text{N} / \mu\text{m}$$

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ADXL-50 Resonance Frequency

- Using a lumped mass-spring approximation:

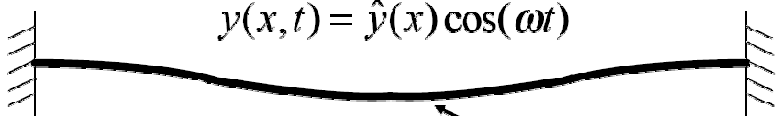
$$f = \frac{1}{2\pi} \sqrt{\frac{k}{M}} = \frac{1}{2\pi} \sqrt{\frac{4.48 \text{ N/m}}{162 \times 10^{-12} \text{ kg}}} = 26.5 \text{ kHz}$$
- On the ADXL-50 Data Sheet: $f_0 = 24 \text{ kHz}$
 - ↗ Why the 10% difference?
 - ↗ Well, it's approximate ... plus ...
 - ↗ Above analysis does not include the frequency-pulling effect of the DC bias voltage across the plate sense fingers and stationary sense fingers ... something we'll cover later on ...

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Distributed Mechanical Structures

- Vibrating structure displacement function:

$$y(x, t) = \hat{y}(x) \cos(\omega t)$$



Maximum displacement function
 (i.e., mode shape function)
 Seen when velocity $\dot{y}(x, t) = 0$
- Procedure for determining resonance frequency:
 - ↪ Use the static displacement of the structure as a trial function and find the strain energy W_{\max} at the point of maximum displacement (e.g., when $t=0, \pi/\omega, \dots$)
 - ↪ Determine the maximum kinetic energy when the beam is at zero displacement (e.g., when it experiences its maximum velocity)
 - ↪ Equate energies and solve for frequency

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Maximum Kinetic Energy

- Displacement: $y(x, t) = \hat{y}(x) \cos[\omega t]$
- Velocity: $v(x, t) = \frac{\partial y(x, t)}{\partial t} = -\omega \hat{y}(x) \sin[\omega t]$
- At times $t = \pi/(2\omega), 3\pi/(2\omega), \dots$



Velocity topographical mapping

- ↪ The displacement of the structure is $y(x, t) = 0$
- ↪ The velocity is maximum and all of the energy in the structure is kinetic (since $W=0$):

$$v(x, (2n + 1) \pi / (2\omega)) = -\omega \hat{y}(x)$$

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Maximum Kinetic Energy (cont)

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- At times $t = \pi/(2\omega), 3\pi/(2\omega), \dots$

$y(x,t) = 0$

Velocity: $v(x, (2n+1)\pi/(2\omega)) = -\omega\hat{y}(x)$

$$dK = \frac{1}{2} \cdot dm \cdot [v(x,t)]^2$$

$$dm = \rho(Wh \cdot dx)$$

- Maximum kinetic energy:

$$K_{\max} = \int_0^L \frac{1}{2} \rho Wh dx v^2(x,t) = \int_0^L \frac{1}{2} \rho Wh \omega^2 \hat{y}^2(x) dx$$

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The Raleigh-Ritz Method

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- Equate the maximum potential and maximum kinetic energies:

$$K_{\max} = \int_0^L \frac{1}{2} \rho Wh \omega^2 \hat{y}^2(x) dx = W_{\max}$$

- Rearranging yields for resonance frequency:

$$\omega = \sqrt{\frac{W_{\max}}{\int_0^L \frac{1}{2} \rho Wh \hat{y}^2(x) dx}}$$

- ω = resonance frequency
- W_{\max} = maximum potential energy
- ρ = density of the structural material
- W = beam width
- h = beam thickness
- $\hat{y}(x)$ = resonance mode shape

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Example: Folded-Beam Resonator

• Derive an expression for the resonance frequency of the folded-beam structure at left.

Use Rayleigh-Ritz method.

$$KE_{max} = PE_{max}$$

Kinetic Energy:

$$KE_{max} = \underbrace{KE_S}_{\text{shuttle}} + \underbrace{KE_t}_{\text{truss}} + \underbrace{KE_b}_{\text{beams}}$$

$$= \frac{1}{2} N_s^2 M_s + \frac{1}{2} N_t^2 M_t + \frac{1}{2} \int N_b^2 dM_b$$

mass of both trusses → Must integrate since the beam velocity is a function of location y!

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Get Kinetic Energies

Velocity of the shuttle: $N_s = \omega_0 \Delta_0$
 Resonance Freq. → Maximum Displacement Amplitude

$$\therefore KE_S = \frac{1}{2} N_s^2 M_s = \frac{1}{2} \omega_0^2 \Delta_0^2 M_s$$

Velocity of the truss: $N_t = \frac{1}{2} N_s = \frac{1}{2} \omega_0 \Delta_0$

$$\therefore KE_t = \frac{1}{2} \left(\frac{1}{2} \omega_0 \Delta_0 \right)^2 M_t = \frac{1}{8} \omega_0^2 \Delta_0^2 M_t$$

Velocity of the beam segments:
 ⇒ assume the mode shape is the same as the static displacement shape
 ⇒ For segment AB:

$$\hat{x}(y) = \frac{F_x}{48 E I_z} (3Ly^2 - 2y^3) \quad 0 \leq y \leq L \quad (1)$$

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Folded-Beam Suspension

Comb-Driven Folded Beam Actuator

$$\hat{x}(y) = \frac{F_x}{48EI_z} (3Ly^2 - 2y^3) \quad 0 \leq y \leq L$$

Case: $y=0 \quad \hat{x}(y=0) = 0 \quad \checkmark$

Case: $y=L \quad \hat{x}(y=L) = \frac{F_x}{48EI_z} L^3 \rightarrow k = \frac{(F_x/4)}{x} = \frac{12EI_z}{L^3} = \frac{k_c}{2} \quad \checkmark$

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Get Kinetic Energies (cont)

At $y=L: x(L) = \frac{x_0}{2} = \frac{F_x L^3}{48EI_z}$

Substituting into (1):

$$\hat{x}(y) = \frac{x_0}{2} \left[3\left(\frac{y}{L}\right)^2 - 2\left(\frac{y}{L}\right)^3 \right]$$

Which yields the velocity:

$$v_b(y)|_{[AB]} = \frac{x_0}{2} \left[3\left(\frac{y}{L}\right)^2 - 2\left(\frac{y}{L}\right)^3 \right] \omega_0$$

Plugging into the expression for KE_b :

$$KE_{[AB]} = \frac{1}{2} \int_0^L \frac{x_0^2 \omega_0^2}{4} \left[3\left(\frac{y}{L}\right)^2 - 2\left(\frac{y}{L}\right)^3 \right]^2 dM_{[AB]}$$

Static mass of beam [AB]:

$$= \frac{x_0^2 \omega_0^2 M_{[AB]}}{8L} \int_0^L \left[3\left(\frac{y}{L}\right)^2 - 2\left(\frac{y}{L}\right)^3 \right]^2 dy$$

$KE_{[AB]} = \frac{13}{280} x_0^2 \omega_0^2 M_{[AB]}$

Anchor $h = \text{thickness}$

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Get Kinetic Energies (cont)

For segment CD:

$$v_b(y)|_{[CD]} = X_0 \left[1 - \frac{3}{2} \left(\frac{y}{L} \right)^2 + \left(\frac{y}{L} \right)^3 \right] \omega_0$$

Thus:

$$KE_{[CD]} = \frac{X_0^2 \omega_0^2 M_{[CD]}}{2L} \int_0^L \left[1 - \frac{3}{2} \left(\frac{y}{L} \right)^2 + \left(\frac{y}{L} \right)^3 \right]^2 dy$$

$$KE_{[CD]} = \frac{83}{280} X_0^2 \omega_0^2 M_{[CD]}$$

Static mass of beam [CD]

Let $M_b \hat{=}$ total mass of the 8 beams.

Then: $M_{[AB]} = M_{[CD]} = \frac{1}{8} M_b$

Thus:

$$KE_b = 4 KE_{[AB]} + 4 KE_{[CD]} = \frac{6}{35} X_0^2 \omega_0^2 M_b$$

and

$$KE_{max} = X_0^2 \omega_0^2 \left[\frac{1}{2} M_s + \frac{1}{8} M_t + \frac{6}{35} M_b \right]$$

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Get Potential Energy & Frequency

PE_{max} is simply the work done to achieve maximum deflection: $= k_c$

$$PE_{max} = \frac{1}{2} k_x X_0^2$$

Thus, using Rayleigh-Ritz:

$$KE_{max} = PE_{max}$$

$$X_0^2 \omega_0^2 \left[\frac{1}{2} M_s + \frac{1}{8} M_t + \frac{6}{35} M_b \right] = \frac{1}{2} k_x X_0^2$$

$$\omega_0 = \left[\frac{k_x}{M_{eq}} \right]^{1/2} = k_c$$

where $M_{eq} = M_s + \frac{1}{4} M_t + \frac{12}{35} M_b$

(Resonance Frequency of a Folded-Beam Suspended Shuttle)

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Brute Force Methods for Resonance Frequency Determination

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Basic Concept: Scaling Guitar Strings

Guitar String

Vib. Amplitude

Low Q

High Q

110 Hz

Freq.

Vibrating "A" String (110 Hz)

Stiffness

Mass

Freq. Equation:

$$f_o = \frac{1}{2\pi} \sqrt{\frac{k_r}{m_r}}$$

Guitar

μMechanical Resonator

Metallized Electrode

W_r

L_r

Anchor

Polysilicon Clamped-Clamped Beam

h_r

[Bannon 1996]

Transmission [dB]

$f_o = 8.5\text{MHz}$

$Q_{vac} = 8,000$

$Q_{air} \sim 50$

Performance:

$L_r = 40.8\mu\text{m}$

$m_r \sim 10^{-13}\text{ kg}$

$W_r = 8\mu\text{m}, h_r = 2\mu\text{m}$

$d = 1000\text{\AA}, V_p = 5\text{V}$

Press. = 70mTorr

Frequency [MHz]

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Anchor Losses

Q = 300 at 70MHz

Problem: direct anchoring to the substrate \Rightarrow anchor radiation into the substrate \Rightarrow lower Q

Solution: support at motionless nodal points \Rightarrow isolate resonator from anchors \Rightarrow less energy loss \Rightarrow higher Q

Q = 15,000 at 92MHz

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92 MHz Free-Free Beam μ Resonator

- Free-free beam μ mechanical resonator with non-intrusive supports \Rightarrow reduce anchor dissipation \Rightarrow higher Q

Design/Performance:
 $L_f = 13.1\mu\text{m}$, $W_f = 6\mu\text{m}$
 $h = 2\mu\text{m}$, $d = 1000\text{\AA}$
 $V_p = 28-76\text{V}$, $W_s = 2.8\mu\text{m}$
 $f_o \sim 92.25\text{MHz}$
 $Q \sim 7,450 @ 10\text{mTorr}$

[Wang, Yu, Nguyen 1998]

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Higher Order Modes for Higher Freq.

2nd Mode Free-Free Beam

3rd Mode Free Free Beam

Distinct Mode Shapes

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Flexural-Mode Beam Wave Equation

$\rho A dx \frac{\partial^2 u}{\partial t^2} = ma$ ← inertial action

Free Body Diagram

• Derive the wave equation for transverse vibration:
 Dynamic Equilibrium Condition for forces in the y-direction: $M + \frac{\partial M}{\partial x} dx$
 $F - (F + \frac{\partial F}{\partial x} dx) - \rho A dx \frac{\partial^2 u}{\partial t^2} = 0$ (1) neglect the $\frac{\partial F}{\partial x} dx$ term

and the moment equilibrium condition: $-F dx + \frac{\partial M}{\partial x} dx \approx 0$ (2)

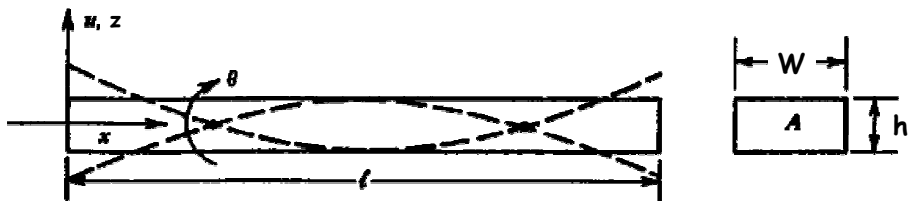
Combining (1) & (2):

$$\frac{\partial^2 M}{\partial x^2} dx = -\rho A dx \frac{\partial^2 u}{\partial t^2} \rightarrow \frac{\partial^2}{\partial x^2} \left(-EI \frac{\partial^2 u}{\partial x^2} \right) = -\rho A \frac{\partial^2 u}{\partial t^2} \rightarrow \frac{\partial^2 u}{\partial t^2} = \left(\frac{EI}{\rho A} \right) \frac{\partial^4 u}{\partial x^4}$$

$$\left[\frac{\partial^2 u}{\partial x^2} = -\frac{M}{EI} \rightarrow M = -EI \frac{\partial^2 u}{\partial x^2} \right]$$

$$I_y = \frac{Wh^3}{12}$$

Example: Free-Free Beam



- Determine the resonance frequency of the beam
- Specify the lumped parameter mechanical equivalent circuit
- Transform to a lumped parameter electrical equivalent circuit
- Start with the flexural-mode beam equation:

$$\frac{\partial^2 u}{\partial t^2} = \left(\frac{EI}{\rho A} \right) \frac{\partial^4 u}{\partial x^4}$$

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Free-Free Beam Frequency

- Substitute $u = u_1 e^{j\omega t}$ into the wave equation:

$$\frac{\partial^4 u}{\partial x^4} = \left(\omega^2 \frac{\rho A}{EI} \right) u \quad (1)$$

- This is a 4th order differential equation with solution:

$$u(x) = \mathcal{A} \cosh kx + \mathcal{B} \sinh kx + \mathcal{C} \cos kx + \mathcal{D} \sin kx \quad (2)$$

Give the mode shape during resonance vibration.

- Boundary Conditions:

At $x = 0$	At $x = \ell$	
$\frac{\partial^2 u}{\partial x^2} = 0$	$\frac{\partial^2 u}{\partial x^2} = 0$	$M = 0$ (Bending moment)
$\frac{\partial^3 u}{\partial x^3} = 0$	$\frac{\partial^3 u}{\partial x^3} = 0$	$\frac{\partial M}{\partial x} = 0$ (Shearing force)

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Free-Free Beam Frequency (cont)

• Applying B.C.'s, get $A=C$ and $B=D$, and

$$\begin{bmatrix} (\cosh k\ell - \cos k\ell) & (\sinh k\ell - \sin k\ell) \\ (\sinh k\ell + \sin k\ell) & (\cosh k\ell - \cos k\ell) \end{bmatrix} \begin{bmatrix} A \\ B \end{bmatrix} = 0 \quad (3)$$

• Setting the determinant = 0 yields

$$\cos k\ell = \frac{1}{\cosh k\ell}$$

• Which has roots at

$$k_1\ell = 4.730 \quad k_2\ell = 7.853 \quad k_3\ell = 10.996$$

• Substituting (2) into (1) finally yields:

$$k^4 = \frac{\rho A}{EI} \omega^2 \rightarrow f_n = \frac{(k_n\ell)^2}{2\pi\ell^2} \sqrt{\frac{EI}{\rho A}} \quad \left[\text{Free-Free Beam Frequency Equation} \right]$$


These values of $k_n\ell$ correspond to the different modes of vibration!

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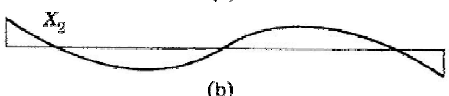
Higher Order Free-Free Beam Modes

Mode	n	Nodal Points	$k_n\ell$	f_n/f_1
Fundamental (f_1)	1	2	4.730	1.000
1st Harmonic	2	3	7.853	2.757
2nd Harmonic	3	4	10.996	5.404
3rd Harmonic	4	5	14.137	8.932
4th Harmonic	5	6	17.279	13.344


← More than 10x increase




(a)



(b)



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Mode Shape Expression


- The mode shape expression can be obtained by using the fact that $A=C$ and $B=D$ into (2), yielding

$$u_x = \mathcal{B} \left[\left(\frac{\mathcal{A}}{\mathcal{B}} \right) (\cosh kx + \cos kx) + (\sinh kx + \sin kx) \right]$$

- Get the amplitude ratio by expanding (3) [the matrix] and solving, which yields

$$\frac{\mathcal{A}}{\mathcal{B}} = \frac{\sin kl - \sinh kl}{\cosh kl - \cos kl}$$

- Then just substitute the roots for each mode to get the expression for mode shape



Fundamental Mode (n=1)
 [Substitute $k_1 l = 4.730$]

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